

INFORMATION DISCLOSURE CITATION IN AN APPLICATION (PTO-1449)				ATTY. DOCKET NO. 49959-118		SERIAL NO. 09/645,690	
				APPLICANT Lizhong Sun, et al.			
				FILING DATE August 24, 2000		GROUP 2812 1746	
U.S. PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
SW	3,889,753	6/17/1975	Richardson				
	4,090,563	5/23/1978	Lybarger, et al.				
	4,541,945	9/17/1985	Anderson, et al.				
	4,954,142	9/4/1990	Carr, et al.				
	5,084,071	1/28/1992	Nenadic, et al.				
	5,225,034	7/6/1993	Yu, et al.				
	5,340,370	8/23/1994	Cadien, et al.				
	5,478,436	12/26/1995	Winebarger, et al.				
	5,527,423	6/18/1996	Neville, et al.				
	5,645,682	7/8/1997	Skrovan				
	5,662,769	9/2/1997	Schonauer, et al.				
	5,509,970	4/23/1996	Shiramizu				
	5,876,508	3/2/1999	Wu, et al.				
✓	5,879,226	3/9/1999	Robinson				
FOREIGN PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						Yes	No
SW	0 401 147	12/5/1990	EPO				
	39 39 661	6/13/1991	DE				
	0 496 605	7/29/1992	EPO				
	2 722 511	1/19/1996	FR				
✓	0 860 860	8/26/1998	EPO				
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)							
SW ↓	Hymes, et al., "The Challenges of the Copper CMP Clean", <i>Semiconductor International</i> , pp. 117-122 (1998).						
	Pak, "Impact of EDTA on Junction and Photolith Qualities", <i>Extended Abstracts</i> , October 1980, vol. 80, no. 2, pp 1241-1243.						
EXAMINER 				DATE CONSIDERED 8/10/02			

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

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U.S. PATENT DOCUMENTS						
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
sw	5,981,454	11/9/1999	Small			
↓	6,033,993	3/7/2000	Love, Jr. et al.			
↓	5,830,280	11/3/1998	Sato, et al.			

FOREIGN PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						Yes	No

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)	
sw	Kern, "Radiochemical Study of Semiconductor Surface Contamination", <i>RCA Review</i> , June 1970, vol. 31, pp 207-264.
↓	Kaufman, F.B., et al., "Chemical-Mechanical Polishing for Fabricating Patterned W Metal Features as Chip Interconnects", <i>J. Electrochem. Society</i> , pp 3460-3465 (1991).
sw	Brusic, V., et al., "Copper Corrosion with and without Inhibitors", <i>J. Electrochem. Soc.</i> , Vol. 138, No. 8, August 1991.
↓	Zhao, et al., "Copper CMP Cleaning Using Brush Scrubbing", February 19-20, 1998 CMP-MIC Conference.

EXAMINER 	DATE CONSIDERED 8/16/02
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